



# Molecular Dynamics Simulations of Hydrogen and Nitrogen Implantation in Tungsten

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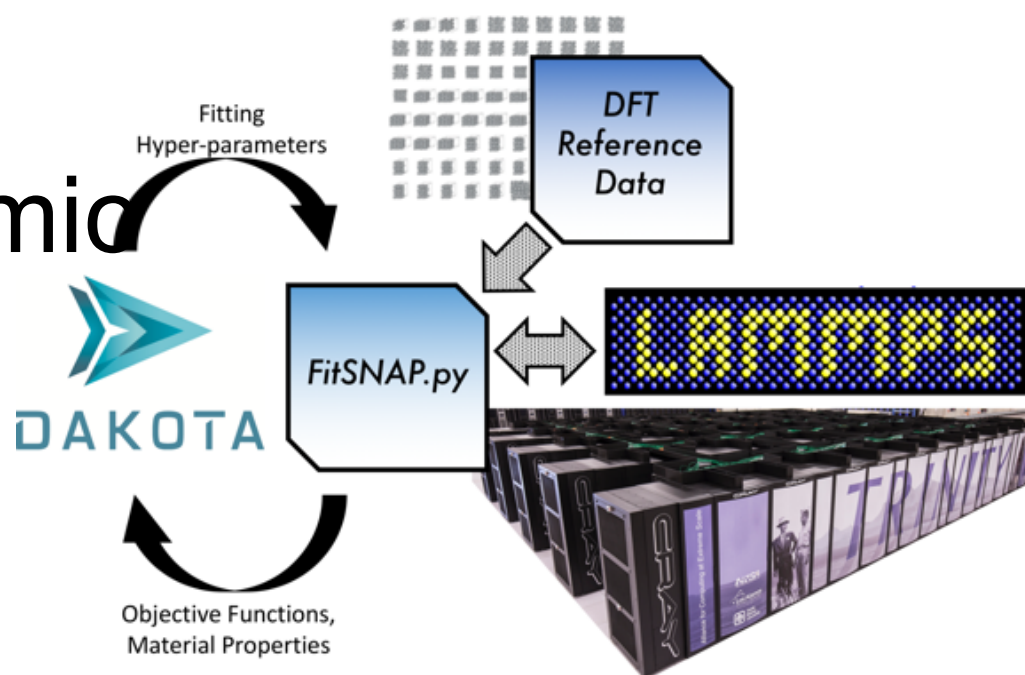
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## Motivation

- Divertor component will be subject to high fluxes of mixed ion species including hydrogen and nitrogen
- Hydrogen retention in reactor components is a concern and better understanding of trapping mechanisms is needed
- Experiments of nitrogen implantation in tungsten has resulted in tungsten nitride formation which increases hydrogen retention<sup>1</sup>
- Critical to understand how tungsten nitrides form and increase hydrogen retention

## SNAP Potential Development

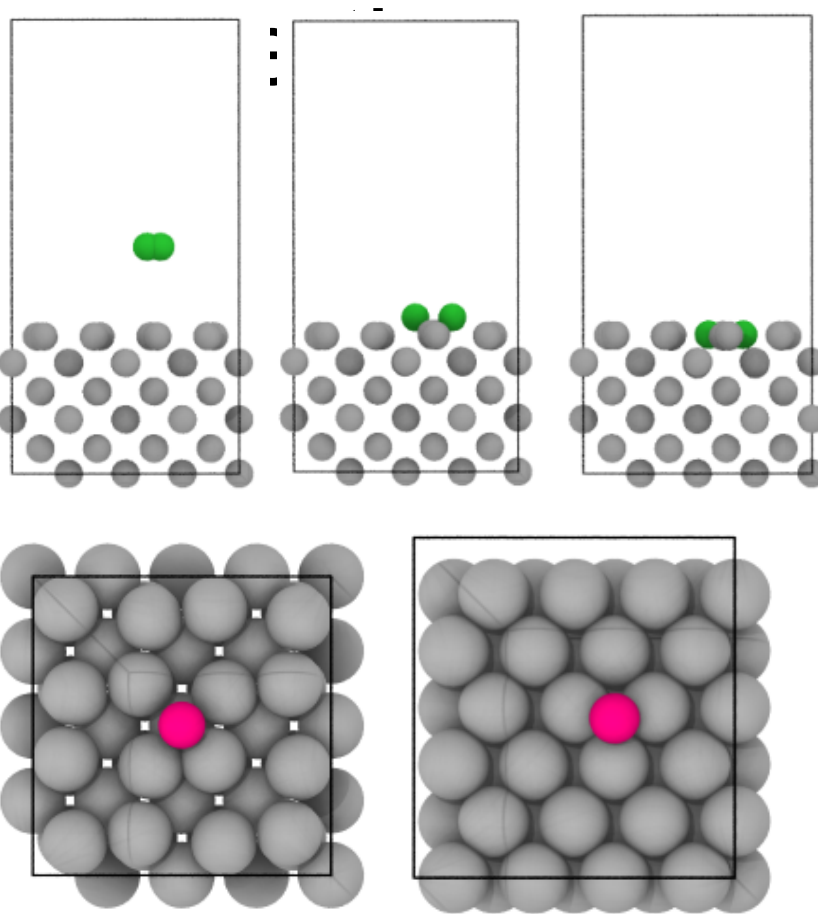
- Few existing potentials for W-H and W-N with limited accuracy
- SNAP<sup>2</sup> is a machine learned interatomic potential trained to DFT data and has improved accuracy<sup>3</sup> compared to traditional potentials
- Extension of W<sup>4,5</sup> SNAP to W-H and W-N



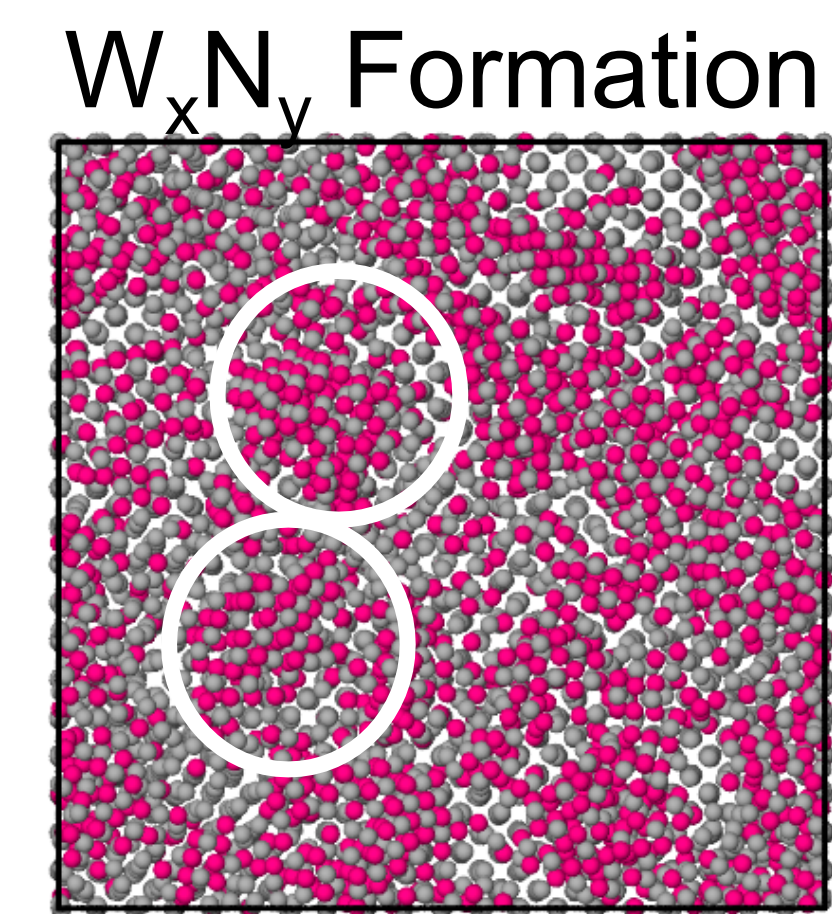
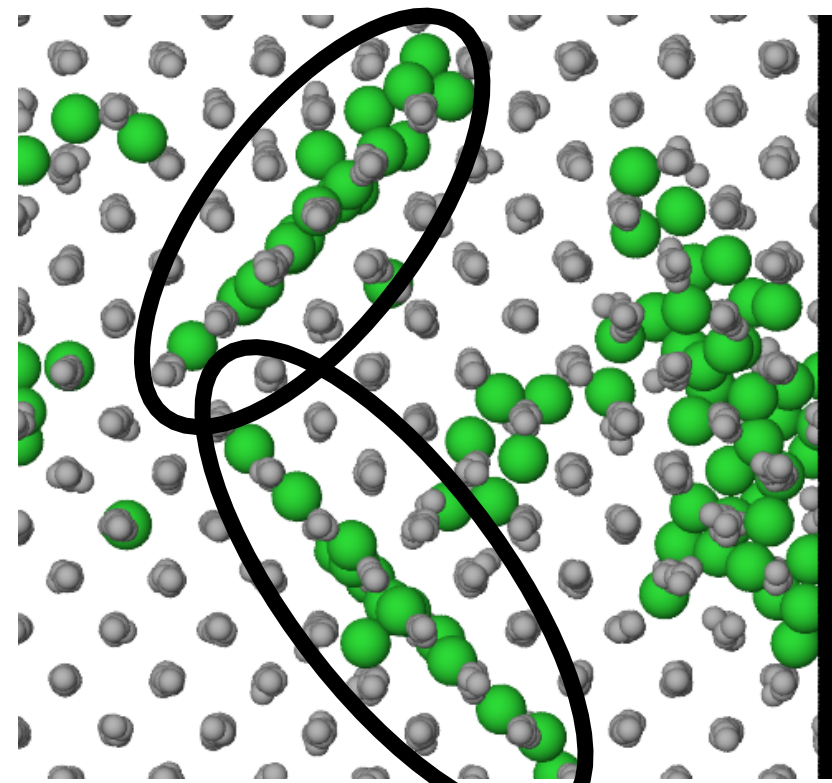
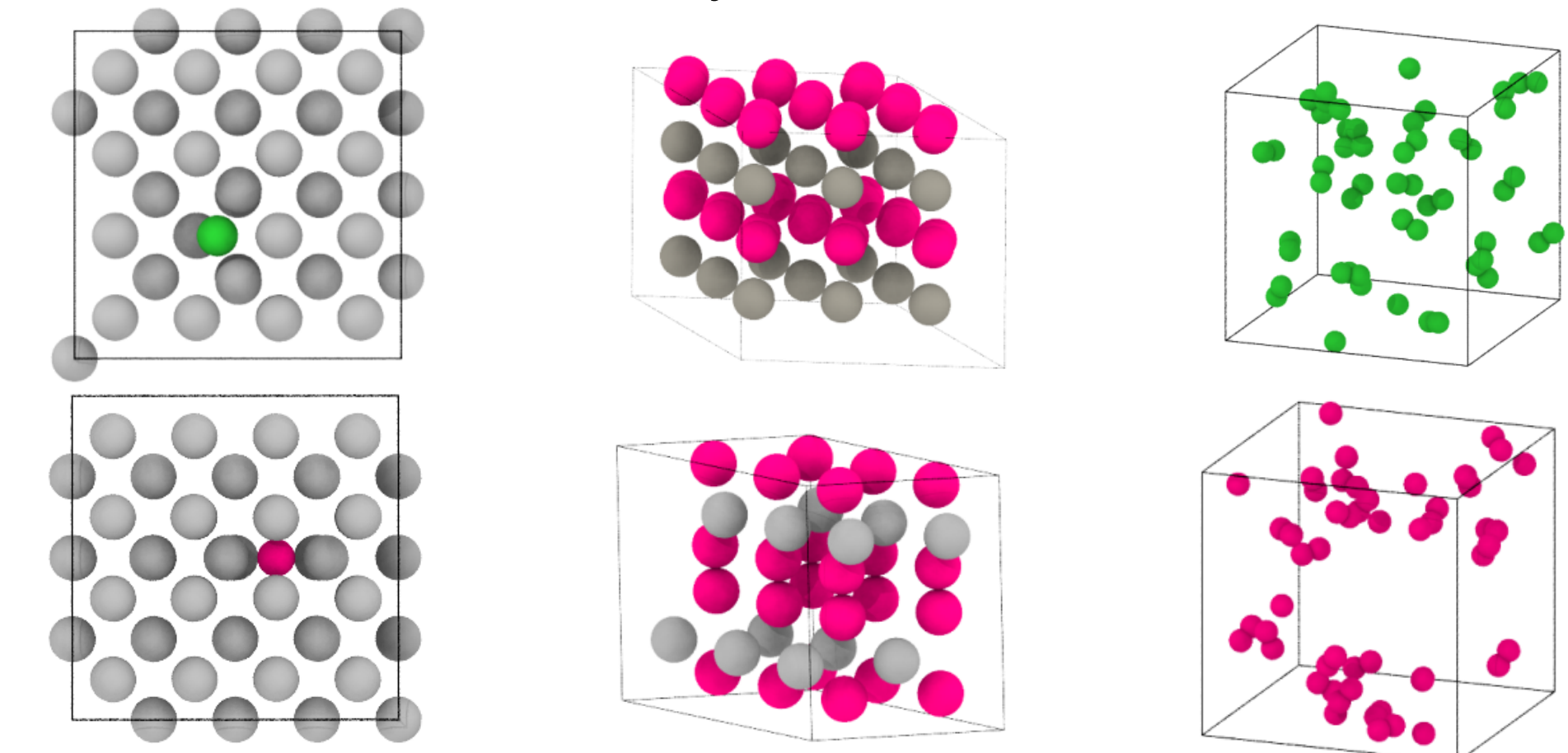
## DFT Training Data

W: Grey H: Green N: Pink

Surface



Bulk Defects W<sub>x</sub>N<sub>y</sub> Structures Gas



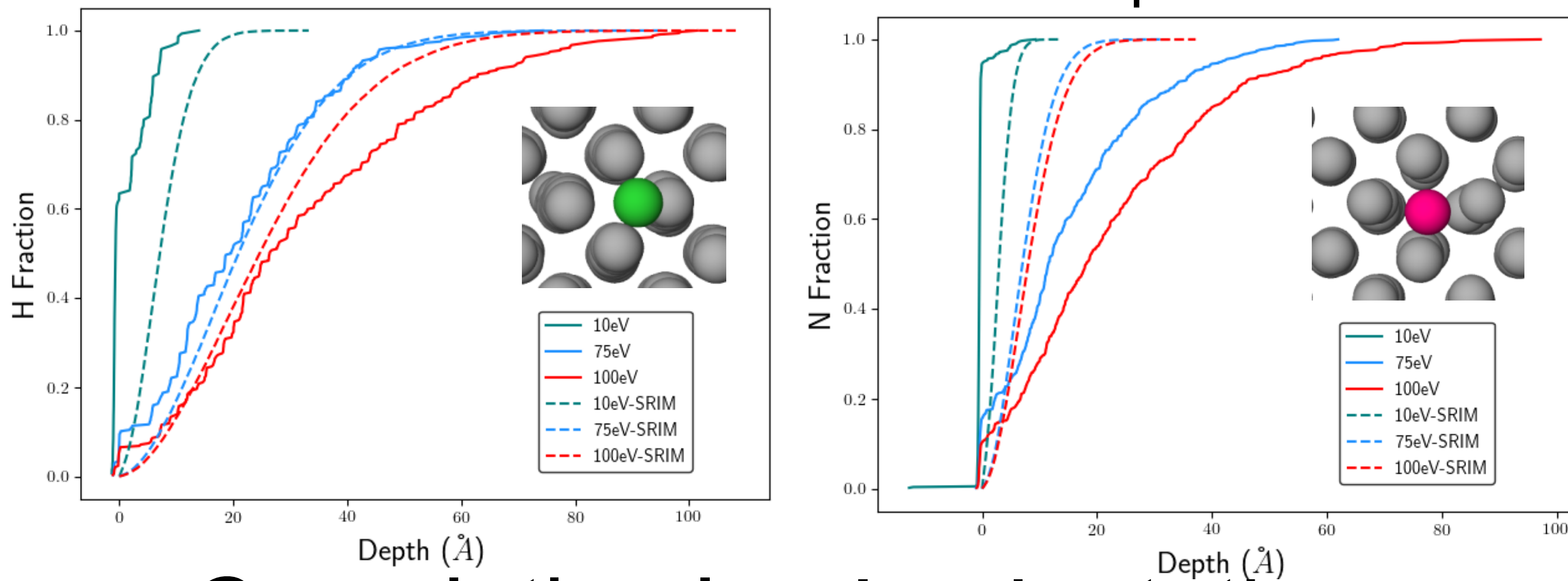
## Fitted Properties

- SNAP can reproduce both gas-phase and condensed-phase chemical interactions
- One set of descriptors for very different atomic species

H Defects	DFT (eV)	SNAP (eV)	N Defects	DFT (eV)	SNAP (eV)
$E_f^{Tet}$	0.88	2.50	$E_f^{Tet}$	1.85	1.89
$E_f^{Oct}$	1.26	3.24	$E_f^{Oct}$	1.11	1.09
$E_f^{Sub}$	4.08	5.38	$E_f^{Sub}$	4.72	2.90
$E_c^{H2}$	-4.74	-4.75	$E_c^{N2}$	-9.79	-9.47
* units in eV					
	P62mmc (WN <sub>2</sub> )	P6m2 (WN <sub>2</sub> )	NiAs (WN)	WC (WN)	MoSi <sub>2</sub> (W <sub>2</sub> N)
DFT	-1.82	-0.91	-0.84	-0.23	-0.03
SNAP	-2.13	-1.45	-0.46	-1.16	0.36

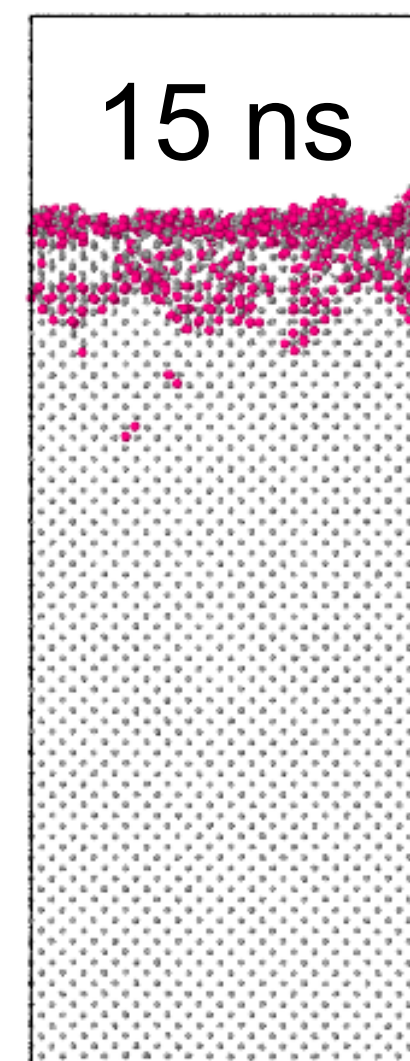
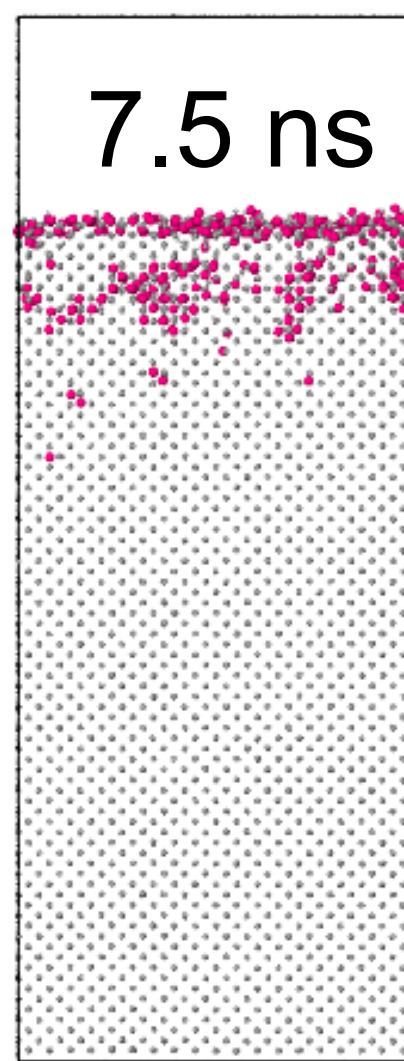
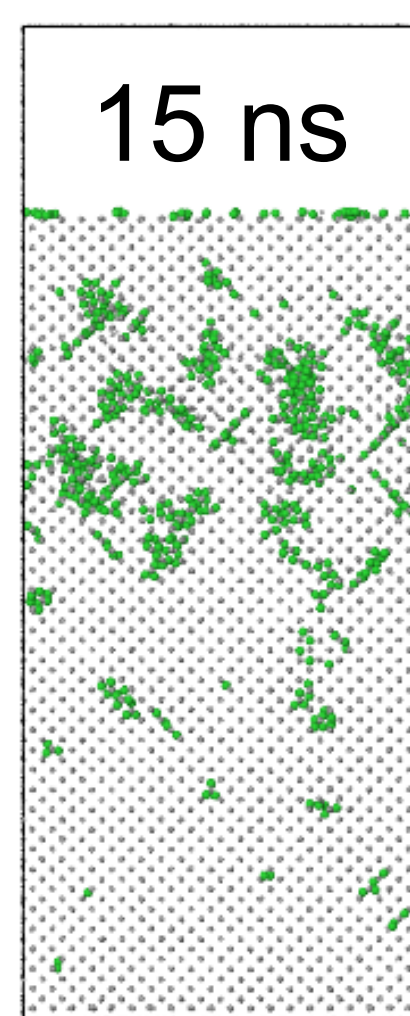
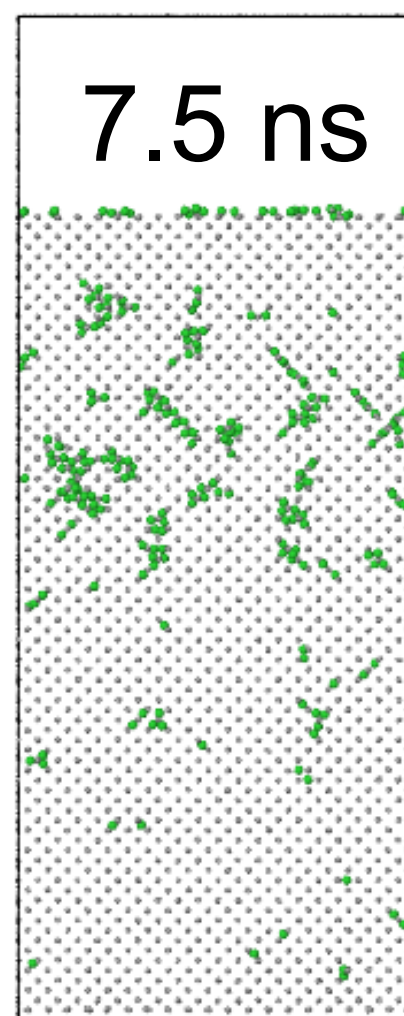
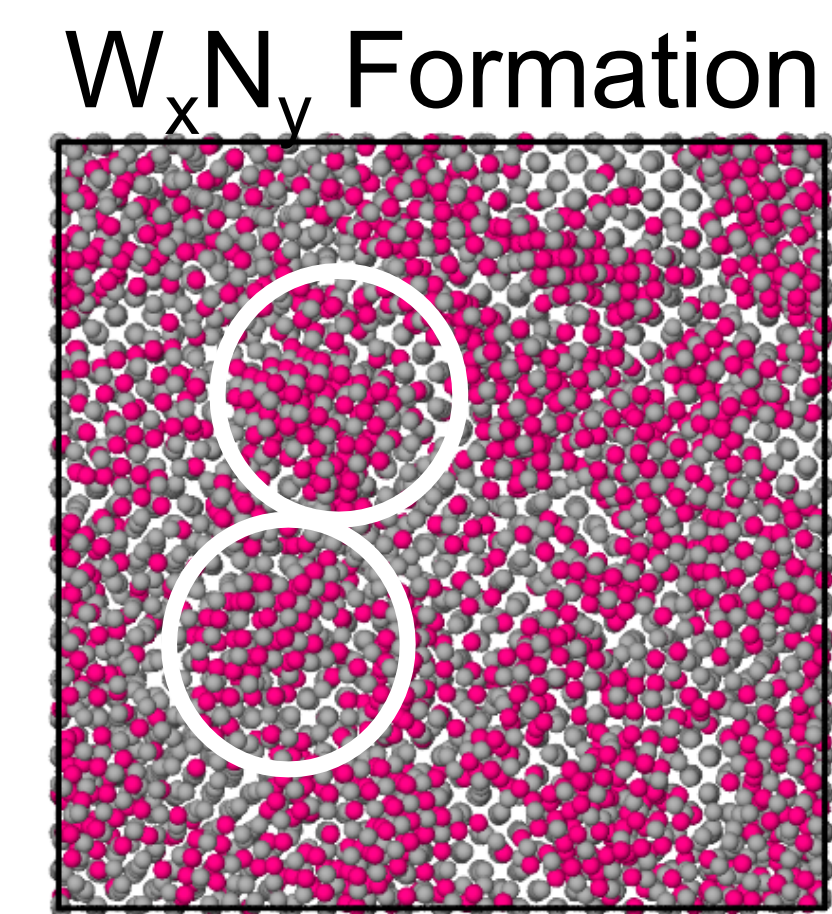
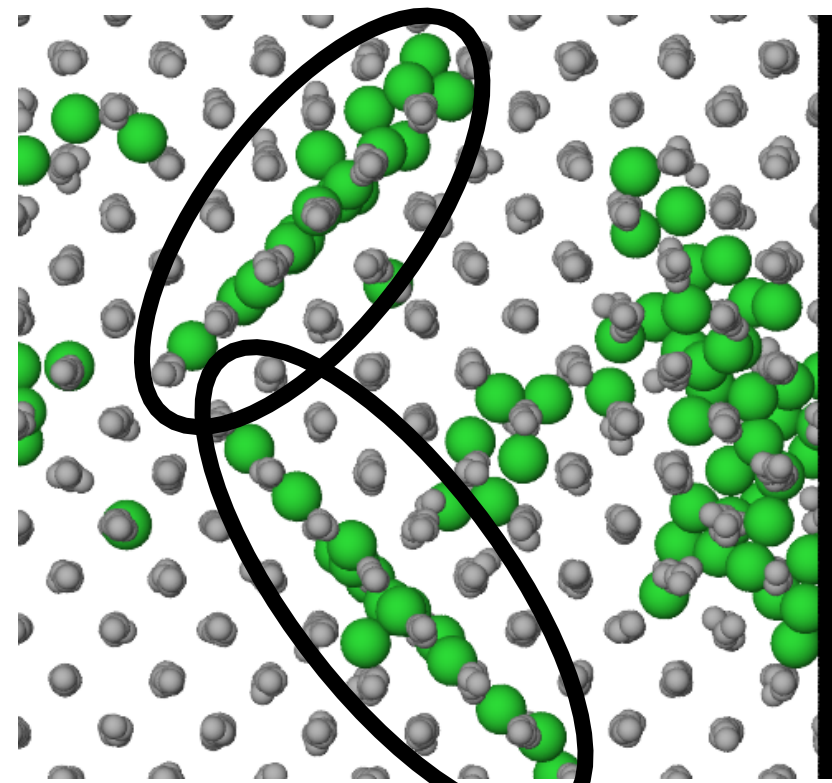
## Single Ion Implantations

- Performed series of single ion implantations to assess depth profile for H and N including comparison with SRIM
- Simulations performed at 1000 K for 10 eV, 75 eV and 100 eV



## Cumulative Ion Implantations

- Performed cumulative ion implantations at 1000 K for 75 eV ion energies where ions are implanted every 10 ps



## Surface Adsorption Energies

H Ads.	DFT (eV)	SNAP (eV)	N Ads.	DFT (eV)	SNAP (eV)
(100) Ads. Site	Bridge	Bridge	(100) Ads. Site	Hollow	Hollow
(100) Ads. Energy	-0.96	-1.57	(100) Ads. Energy	-3.52	-4.33
(100) H <sub>2</sub> Ads. Energy	-0.80	-0.76	(100) N <sub>2</sub> Ads. Energy	-2.94	-8.63
(110) Ads. Site	Hollow	Hollow	(110) Ads. Site	Hollow	Bridge
(110) Ads. Energy	-0.75	-0.69	(110) Ads. Energy	-3.59	-2.58
(111) Ads. Site	Bridge	Bridge	(111) Ads. Site	Bridge	Hollow
(111) Ads. Energy	-0.59	-1.42	(111) Ads. Energy	-3.08	-3.44

- Nitrogen defects and W<sub>x</sub>N<sub>y</sub> energies well reproduced
- H surface properties well reproduced but tradeoff in defect energies

N surface energetics good but wrong site predicted for some surfaces